

Micropatterning Japan TC Meeting Summary and Minutes

SEMI Japan Standards Summer 2015 Meetings

Thursday, October 15, 2015, 15:30-17:00

SEMI Japan, Tokyo, Japan

Next Committee Meeting

SEMI Japan Standards Winter 2016 Meetings

Thursday, January 28, 2016, 15:30-18:00

SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs: Morihisa Hoga (Dai Nippon Printing)

SEMI Staff: Junko Collins (SEMI Japan)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Dai Nippon Printing	Hoga	Morihisa	Dai Nippon Printing	Suzuki	Toshio
-	Otaki	Masao	SEMI Japan	Collins	Junko

Table 2 Leadership Changes

None

Table 3 Ballot Results

Doc. #5229A, Revision to SEMI P44-0211, Specification for Open Artwork System interchange Standard (OASIS®) Specific to Mask Tools Failed and returned to the task force

Table 4 Authorized Ballots

<i>#</i>	<i>When</i>	<i>SC/TF/WG</i>	<i>Details</i>

None

Table 5 Authorized Activities

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>

None

Table 6 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
MP121015-1	Toshio Suzuki	To submit 5229B to Cycle 8
MP121015-2	Morihisa Hoga	To complete the document list to identify which document should be inactive status with respect to the document which were originated by Japan TC Chapter
MP121015-3	Toshio Suzuki	To communicate with stakeholders who requested the SNARF 5366: Revision to P45, about “inactive” status for P45.

1 Welcome, Reminders and Introductions

Morihisa Hoga, committee co-chair, called the meeting to order at 15:30. Self-introductions were made followed by the agenda review.

2 Required Meeting Elements

The meeting reminders on program membership requirement, antitrust issues, intellectual property issues and international effective meeting guidelines, were reviewed by SEMI staff, Junko Collins.

Attachment: Required_Elements_Reg_20150327_E+J

3 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on October 15, 2015.

Motion: To approve the minutes of the previous meeting as submitted.

By / 2nd: Toshio Suzuki (Dainippon Printing) / Masako Otaki (-)

Discussion: None

Vote: 2 in favor and 0 opposed. **Motion passed.**

4 SEMI Staff Report

Junko Collins gave the SEMI staff report. This report included SEMI Global Calendar of Events, Global Standards Meeting Schedule, Critical Dates for SEMI Standards Ballots, SEMI Standards Publication and Contact Information.

Attachment: SEMI Staff Report 2015.10.15

5 Liaison Reports

5.1 *Microlithography North America TC Report*

Participants reviewed the meeting minutes during SEMCON West 2015.

Next meeting is scheduled on February 24 in conjunction with SPIE Advanced Lithography Conference at San Jose, California.

Attachment: NA Microlithography Minutes 2015 West

6 Ballot Review

6.1 Doc. #5229A, Revision to SEMI P44-0211, Specification for Open Artwork System interchange Standard (OASIS®) Specific to Mask Tools

Attachment: 5229A Ballot report

7 Task Force Reports

7.1 *Mask Data Format for Mask Tools Task Force*

Toshio Suzuki reported for the Mask data Format for Mask Tools Task Force. Of note:

- *Doc. #5229A, Revision to SEMI P44-0211, Specification for Open Artwork System interchange Standard (OASIS®) Specific to Mask Tools, failed. Task Force will be submitted for cycle 8.*

- Toshio Suzuki will communicate with stakeholder who requested SNARF 5366: Revision to P45, about “inactive” status of P45.

7.2 5 Year Review Task Force

Masao Otaki reported on progress for the 5 Year Review Task Force, but no special report for this time.

8 Old Business

8.1 Previous Meeting Action Items

Junko Collins reviewed the previous meeting action items.

Table 7 Previous Meeting Actions Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
MP150625-1	Toshio Suzuki	Submit 5229A to Cycle 6 by Suzuki-san Closed

8.2 Standards Document Development Project Period

No related document for this time.

8.3 Disbandment of this TC chapter

Since 5229A failed the TC Chapter review, this TC Chapter will be disbanded at or later the next TC Chapter meeting.

9 New Business

None

10 Action Item Review

10.1 New Action Items

Junko Collins reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

11 Next Meeting and Adjournment

The next meeting of the Micropatterning Japan TC meeting is scheduled for Thursday, January 28, 2016, 15:30-18:00, at SEMI Japan, Tokyo, Japan.

Respectfully submitted by:
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SEMI Japan
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Minutes approved by:

Morihisa Hoga (Dai Nippon Printing), Co-chair	MH
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Table 8 Index of Available Attachments #1

	<i>Title</i>
	Required_Elements_Reg_20150327_E+J
	SEMI Staff Report 2015.10.15
	NA Microlithography Minutes 2015 West
	5229A Ballot report

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Junko Collins at the contact information above.